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TC 1700 PTO/SB/21 (08-00)

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U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

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| TRANSMITTAL FORM (to be used for all correspondence after initial filing) | Application Number | 09/934,248 |
| | Filing Date | 08/21/2001 |
| | First Named Inventor | Choi et al. |
| | Group Art Unit | 3682 |
| | Examiner Name | Unassigned |
| Total Number of Pages in This Submission | Attorney Docket Number | PA19-09V07 |

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| ENCLOSURES (check all that apply) | | |
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| SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT | |
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| Signature | <i>Kenneth C. Brooks</i> |
| Date | 2/28/03 |

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Choi et al.

PATENT APPLICATION

Serial No.: 09/934,248

Group Art Unit: 3682

Filing Date: August 21, 2001

Examiner: Unassigned

For: FLEXURE BASED MACRO MOTION TRANSLATION STAGE

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INFORMATION DISCLOSURE STATEMENT

Commissioner
for Patents
Washington, D.C. 20231

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure under 37 C.F.R. § 1.56. Form PTO-1449 and a copy of each reference recited below accompanies this document. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

ISSUED PATENTS

| <u>Patent Number</u> | <u>Inventor</u> | <u>Grant Date</u> |
|----------------------|-----------------|-------------------|
| 4,440,804 | Milgram | Apr. 3, 1984 |
| 4,544,572 | Sandvig et al. | Oct. 1, 1985 |
| 5,723,176 | Keyworth et al. | Mar. 3, 1998 |
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| 6,245,213 | Olsson et al. | Jun. 12, 2001 |

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PENDING PATENT APPLICATIONS

| <u>Serial Number</u> | <u>Inventor</u> | <u>Filing Date</u> |
|----------------------|--------------------|--------------------|
| 09/698,317 | Choi et al. | Oct. 27, 2000 |
| 09/907,512 | Sreenivasan et al. | Jul. 16, 2001 |
| 09/908,455 | Choi et al. | Jul. 17, 2001 |
| 09/908,765 | Willson et al. | Jul. 19, 2001 |
| 09/920,341 | Choi et al. | Aug. 1, 2001 |

FOREIGN PATENT DOCUMENTS

| <u>Document Number</u> | <u>Inventor</u> | <u>Pub. Date</u> |
|------------------------|-----------------|------------------|
| WO 92/17883 | Olsson | Oct. 15, 1992 |
| WO 98/10121 | Olsson et al. | Mar. 12, 1998 |
| WO 99/45753 | Wikström | Sep. 10, 1999 |
| WO 99/63535 | Olsson | Dec. 9, 1999 |
| WO 01/53889 | Ling et al. | Jul. 26, 2001 |

NON-PATENT DOCUMENTS

Lin, "Multi-Layer Resist Systems", Introduction of Microlithography", American Chemical Society, 1983, pp. 287-350, IBM T.J. Watson Research Center, Yorktown Heights, NY 10598.

Cowie, "Polymers: Chemistry and Physics of Modern Materials", 1991, pp. 408-409, 2nd Ed, Chapman and Hall, a division of Routledge, Chapman and Hall, Inc., 29 West 35th Street, NY, NY 10001-2291.

Chou et al., "Imprint of Sub-25nm Vias and Trenches in Polymers", Applied Physics Letters, Nov. 20, 1995, pp. 3114-3116, vol. 67(21).

Chou et al., "Imprint Lithography with 25-Nanometer Resolution",
Science, Apr. 5, 1996, pp. 85-87, vol. 272.

Chou et al., "Imprint Lithography with Sub-10nm Feature Size and
High Throughput", Microelectronic Engineering, 1997, pp. 237-240,
vol. 35.

Xia et al., "Soft Lithography", Agnew. Chem. Int. Ed., 1998, pp.
550-575, vol. 37.

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Date: 02.28.03

Respectfully Submitted,



Kenneth C. Brooks
Reg. No. 38,393

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

1

of

2

Application Number

09/934,248

Filing Date

08/21/2001

First Named Inventor

Choi et al.

Group Art Unit

3682

Examiner Name

Unassigned

Attorney Docket Number

PA19-09V07

U.S. PATENT DOCUMENTS

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Signature

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| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary) | | Application Number | 09/934,248 |
| | | Filing Date | 08/21/2001 |
| | | First Named Inventor | Choi et al. |
| | | Group Art Unit | 3682 |
| | | Examiner Name | Unassigned |
| Sheet 2 of 2 | Attorney Docket Number | PA19-09V07 | |

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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|----------|---|----------------|
| OIP | B18 | LIN, "Multi-Layer Resist Systems", Introduction of Microlithography, American Chemical Society, 1983, pp. 287-350, IBM T.J. Watson Research Center, Yorktown Heights, New York 10598. | |
| | B19 | COWIE, "Polymers: Chemistry and Physics of Modern Materials", 1991, pp. 408-409, 2 nd Ed, Chapman and Hall, a division of Routledge, Chapman and Hall, Inc., 29 West 35 th Street, NY, NY 10001-2291. | |
| | B20 | CHOU et al., "Imprint of Sub-25 nm Vias and Trenches in Polymers", Applied Physics Letters, November 20, 1995, pp. 3114-3116, vol. 67(21). | |
| | B21 | CHOU et al., "Imprint Lithography with 25-Nanometer Resolution", Science, Apr. 5, 1996, pp. 85-87, vol. 272. | |
| | B22 | CHOU et al., "Imprint Lithography with Sub-10nm Feature Size and High Throughput", Microelectronic Engineering, 1997, pp. 237-240, vol. 35. | |
| | B23 | XIA et al., "Soft Lithography", Agnew. Chem. Int. Ed., 1998, pp. 550-575, vol. 37. | |
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